I CLAIM:

1. A structure of a laser cleaning machine comprising:

(a) a laser generation device for cleaning a to-be-cleaned object having a plurality of contactor elements configured at intervals thereon;

(b) a platform for supporting the to-be-cleaned object under a projection path of the laser generation device;

(c) an image capture device configured on the laser generation device comprising a first capturing element comprising a lower-powered lens for obtaining location distribution information of the contactor elements and a second capturing element comprising a higer-powdered lens for obtaining precise coordinate information of the contactor elements, located to a side of the first capturing element; and

(d) a cleaning and control device inside the image capturing device for setting a traversal path of the laser generation device and for processing information obtained by the image capturing device.

~~2. The structure of a laser cleaning machine according to claim 1, wherein there are a plurality of contactor elements configured at intervals on the to-be-cleaned object.~~

~~3. The structure of a laser cleaning machine according to claim 2, wherein the first capturing element comprises a lower-powered lens for obtaining location distribution information of the contactor~~

~~elements.~~

~~4. The structure of a laser cleaning machine according to claim 2, wherein the second capturing element comprises a higher-powered lens for obtaining precise coordinate information of the contactor elements.~~

~~5~~2. The structure of a laser cleaning machine according to claim 1, further comprising (e) a control device on the platform for controlling the laser generation device and the image capture device.

~~6~~3. The structure of a laser cleaning machine according to claim 1, wherein the laser generation device comprises a pair of linear sliding rails and a rack moveably configured on the sliding rails, and ~~.~~

7. ~~The structure of a laser cleaning machine according to claim 1, wherein the laser generation device~~ has an AC charging voltage between 650V and 1,000V.

~~8~~4. The structure of a laser cleaning machine ~~according to claim 1~~any of claims 1 to 3, wherein a wave length produced by the laser generation device is between 532 nm and 1,064 nm~~.~~ and

~~9. The structure of a laser cleaning machine according to claim 1, wherein~~ a pulse energy produced by the laser generation device is between 400 mJ and 1,200 mJ.

~~10~~5. The structure of a laser cleaning machine according to claim 1, wherein the to-be-cleaned object is one of a cantilever probe card, a vertical probe card, a membrane probe card, a pogo probe card, a

micro spring probe card, and a Micro Electro Mechanical System (MEMS) probe card.